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OS15-01 Multi-wavelength interferometer for measuring absolute distances using numerous frequency modes of the electro-optic comb

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OS15-02 An Optical Angle Measurement Based on Dual Comb Spectroscopy

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OS15-03 Calibration Method for Optical Angle Measurements using Diffraction Gratings

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Asit Kumar Gain, Liangchi Zhang and Zhen Li

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